



Contribution ID: 193

Type: Oral

EUV EMISSION FROM HIGHLY CHARGED TIN IONS IN AN EBIT

Keywords

EUV
EBIT
Sn plasma

Topics

Fundamental Aspects, Structure and Spectroscopy

Primary author: SCHEERS, Joris (Advanced Research Center for Nanolithography)

Co-authors: Dr SHAH, Chintan (Max-Planck-Institut für Kernphysik, Heidelberg); Dr BEKKER, H (Max Planck Institute for Nuclear Physics); Dr WINDBERGER, A (Advanced Research Center for Nanolithography); Mr TORRETTI, F (Advanced Research Center for Nanolithography); Prof. UBACHS, W (Vrije Universiteit Amsterdam); Prof. HOEKSTRA, R (University of Groningen); Mr CRESPO LÓPEZ-URRUTIA, José R. (Max-Planck-Institut für Kernphysik); Dr VERSOLATO, O O (ARCNL)

Presenter: SCHEERS, Joris (Advanced Research Center for Nanolithography)